## Notice of References Cited Application/Control No. 10/668,783 Applicant(s)/Patent Under Reexamination TUMMALA ET AL. Examiner Jean M. Corrielus Art Unit Page 1 of 1

## **U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	Α	US-2005/0273570	12-2005	DeSouter et al.	711/203
*	В	US-2005/0193245	09-2005	Hayden et al.	714/013
*	С	US-2005/0065985	03-2005	Tummala et al.	707/201
*	D	US-2005/0015663	01-2005	Armangau et al.	714/015
*	Е	US-2004/0267836	12-2004	Armangau et al.	707/203
*	뚜	US-2004/0107222	06-2004	Venkatesh et al.	707/200
*	O	US-2004/0030951	02-2004	Armangau, Philippe	714/6
*	Ξ	US-2004/0030846	02-2004	Armangau et al.	711/154
*	1	US-2004/0030727	02-2004	Armangau et al.	707/200
*	J	US-6,957,362	10-2005	Armangau, Philippe	714/20
*	К	US-6,934,822	08-2005	Armangau et al.	711/162
*	L	US-6,792,518	09-2004	Armangau et al.	711/162
*	М	US-2003/0182253	09-2003	Chen et al.	707/1

## **FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	0					
	P					
	σ					
	R					
	S					
	Т					

## **NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	
	٧	
	W	
	х	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.